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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No. 09/141,775
Priority Filing Date August 27, 1998
Inventor Guy T. Blalock et al.
Priority Group Art Unit 1765
Priority Examiner L. Vinh
Attorney's Docket No. MI22-1544
Title: Plasma Etching Methods

PRELIMINARY AMENDMENT

To: Box Patent Application
Assistant Commissioner for Patents
Washington, D.C. 20231

From: Bernard Berman (Tel. 509-624-4276; Fax 509-838-3424)
Wells, St. John, Roberts, Gregory & Matkin P.S.
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Sir:

Please enter the following amendments prior to examining the above-identified application.

AMENDMENTS

In the Specification

At p. 1, before the "Technical Field" section, please replace the existing Related Applications section with the following:

--RELATED PATENT DATA

This patent is a continuation application of U.S. Patent Application Serial No. 09/141,775, which was filed on August 27, 1998, entitled "Plasma Etching Methods," naming Guy T. Blalock, David S. Becker, and